

Searching Novel Higher- κ Dielectric Materials Through High-throughput *Ab Initio* Approach

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High throughput for new high-k materials

High-k Dielectric reduces leakage substantially

Gate
1.2nm SiO₂
Silicon substrate

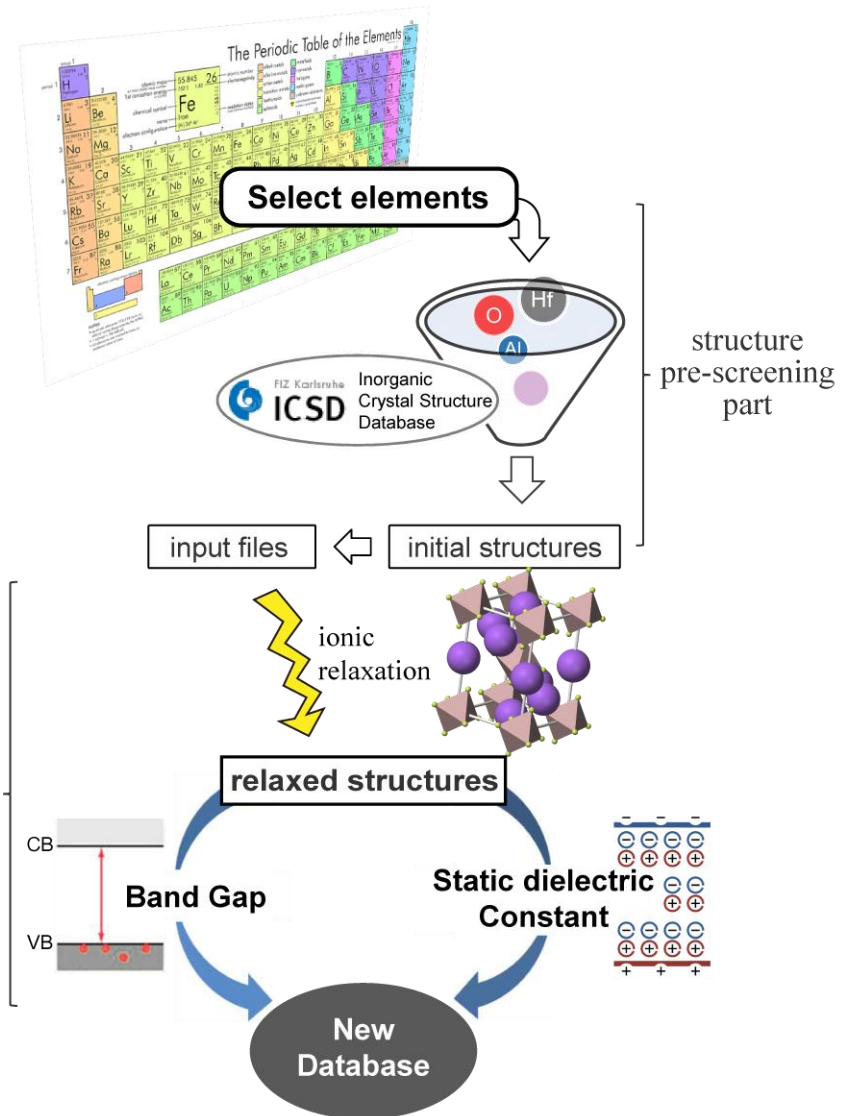
Gate
3.0nm High-k
Silicon substrate

Benefits compared to current process technologies

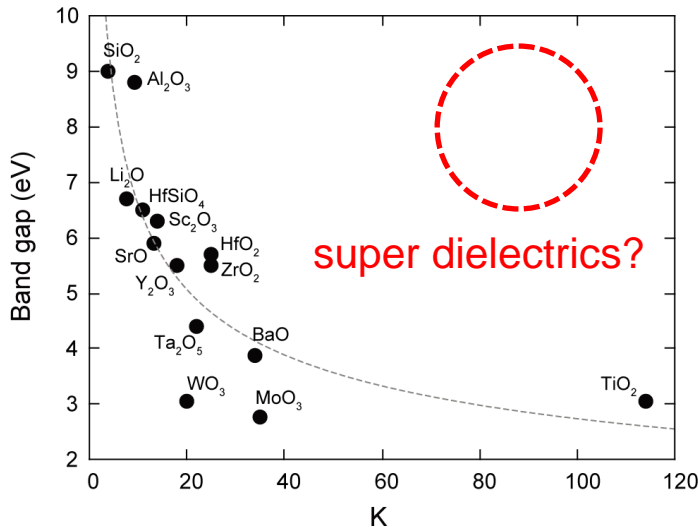
	High-k vs. SiO ₂	Benefit
Capacitance	60% greater	Much faster transistors
Gate dielectric leakage	> 100x reduction	Far cooler

intel

- Automation for High-throughput calculation



- Ideal condition of high-k dielectrics : Large permittivity(κ) and large band gap(E_g)



III. Result: Materials map for high- κ dielectrics

- Property Map of ~1,800 oxides
(metallic and unstable data are excluded on the map)

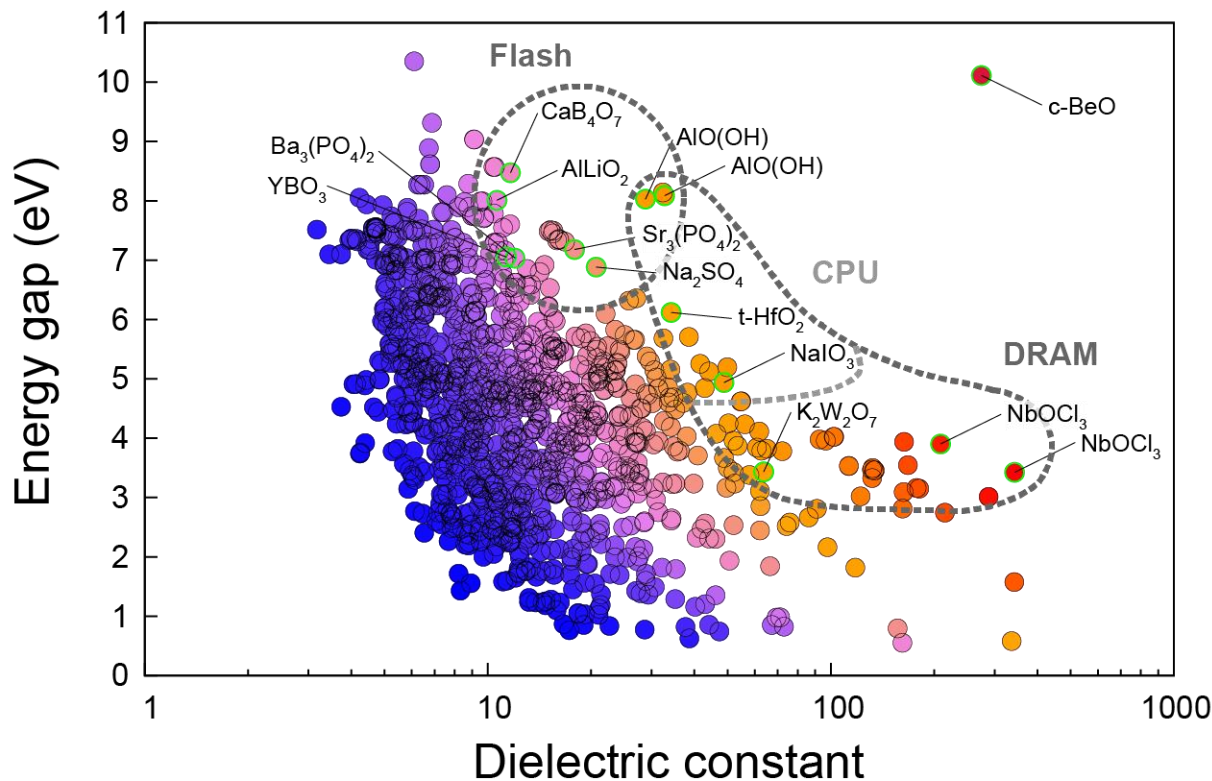


Figure of merits of leakage current : $f = E_g \cdot \kappa$ (approximated)

[DRAM]

- $f_{FOM} > 210$
- $E_g > 3$ eV and $\kappa > 30$

[CPU]

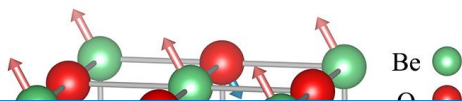
- $f_{FOM} > 210$
- $E_g > 4$ eV
- $E_{vac} > 5.6$ eV

[Flash]

- $f_{FOM} > 80$
- $E_g > 6$ eV

III. Result: New high-k candidate materials

- c-BeO (rocksalt, high pressure)



- **Two common features for ternary higher-k candidates**

- ① **Cations in edge-shared octahedra cage**

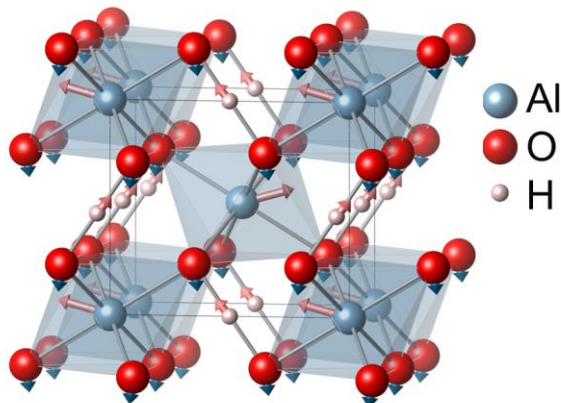
- ✓ Edge-shared anion octahedra form loose cages.
- ✓ Cations in the cages vibrate with soft phonon frequency.

- ② **Channeled structure by strong covalent oxide unit**

- ✓ Strong covalent oxide unit + loosely bound cation
- ✓ Channeled structure : ions easily vibrate along the channel that is not blocked by other ions.

- **AlO(OH)**

$\omega = 6.51$ THz



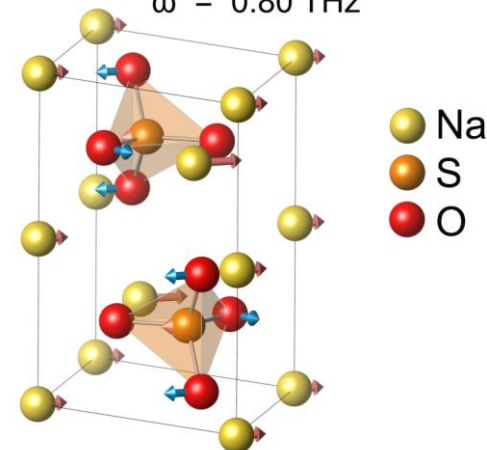
ϵ^∞ : 3.2

ϵ^0 : 32.8

E_g : 8.1 eV

- **Na₂SO₄**

$\omega = 0.80$ THz



ϵ^∞ : 2.3

ϵ^0 : 20.7

E_g : 6.9 eV